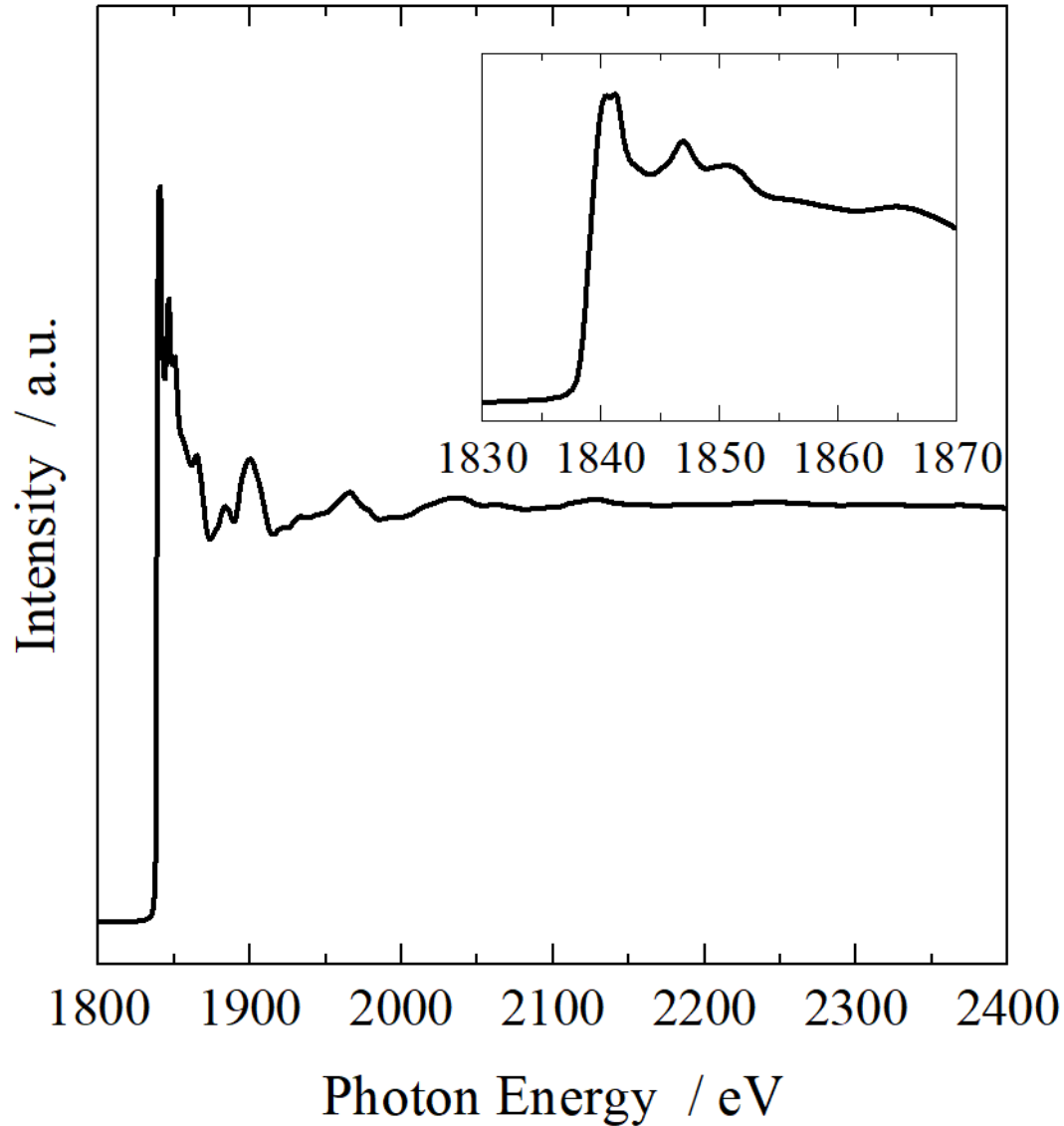
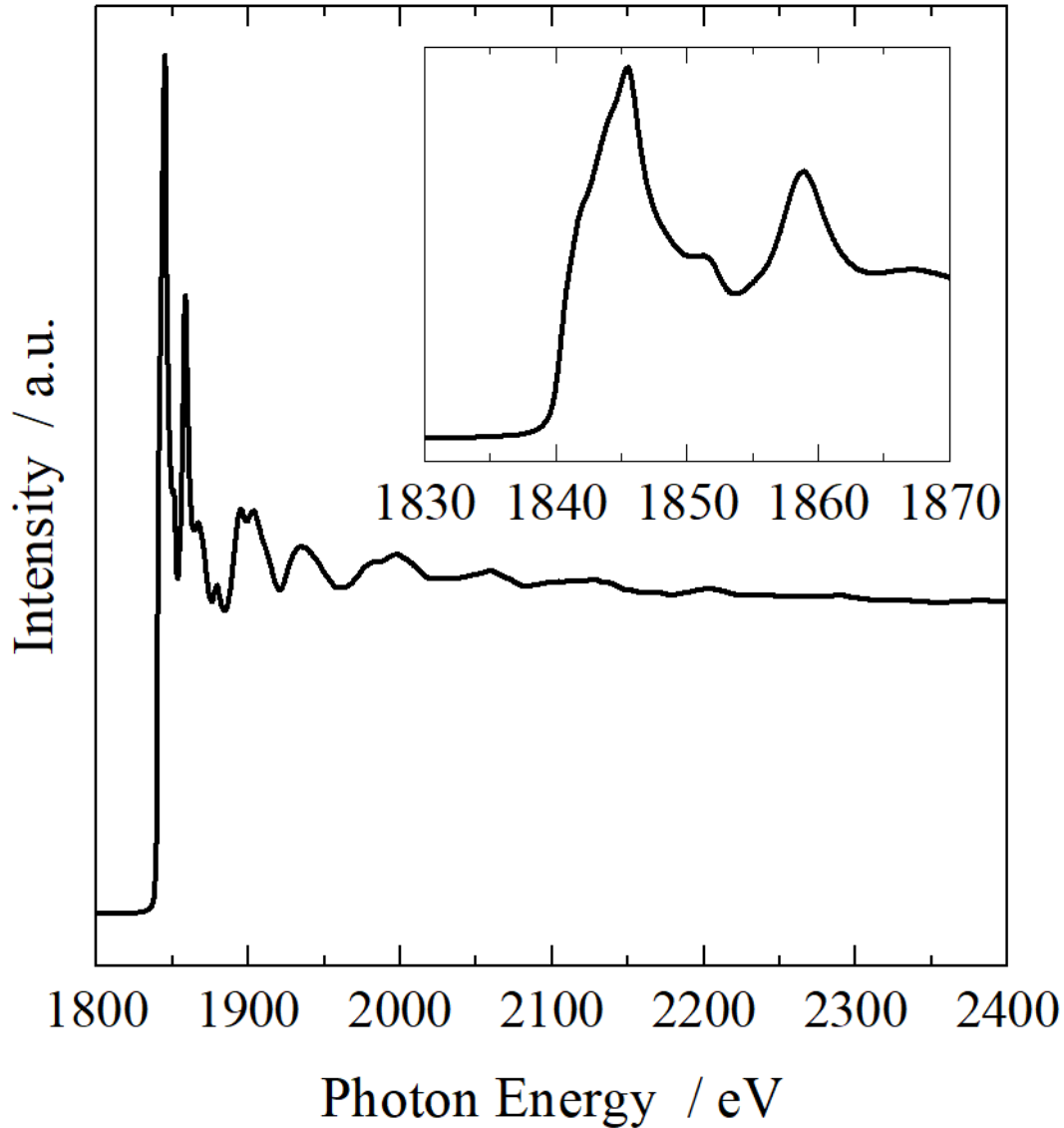


## Si K-edge



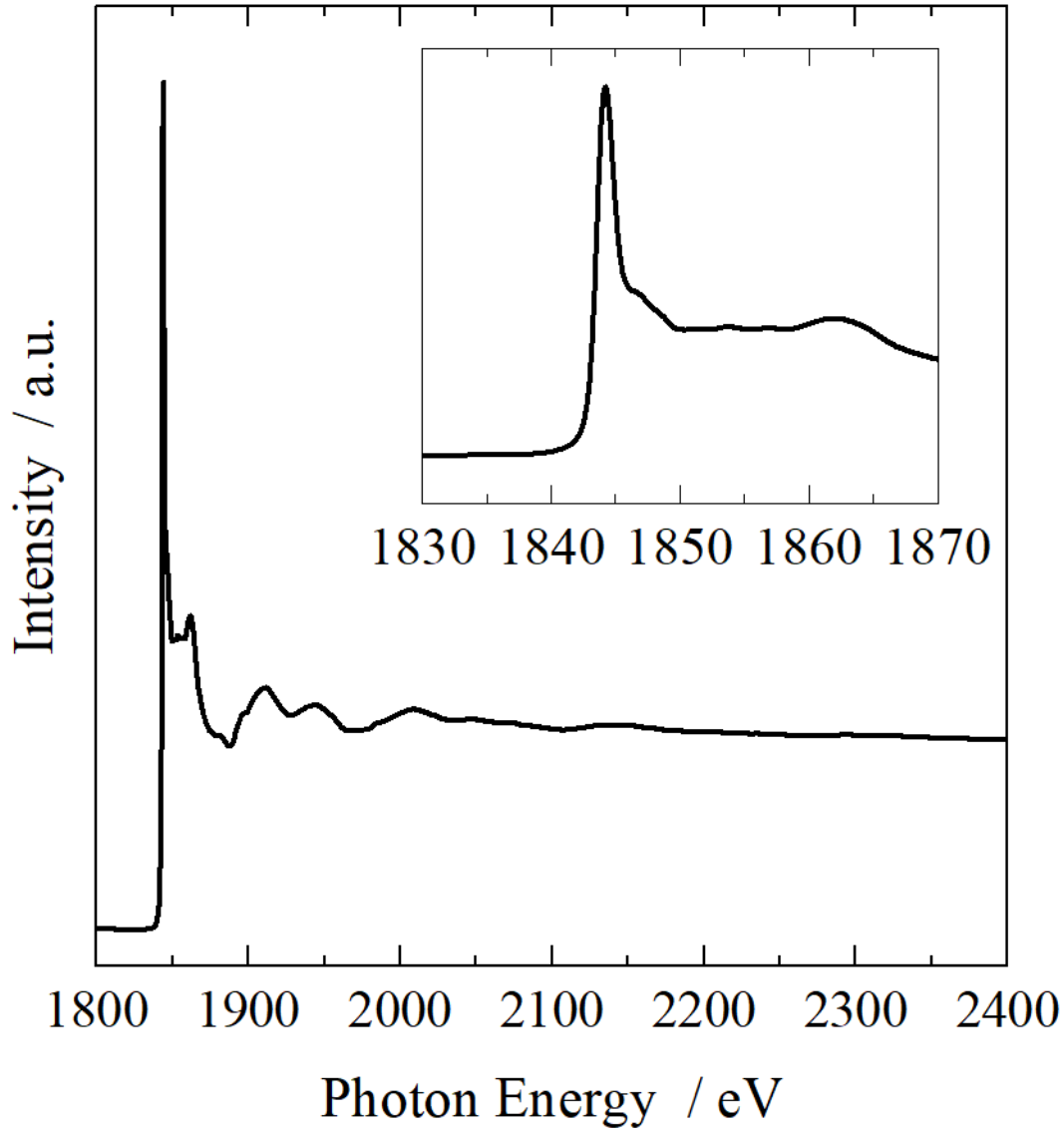
Sample	Si wafer (with natural oxidized film)
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	2 s
Total points	339 points
Total meas. Time	About 19 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing

## Si K-edge



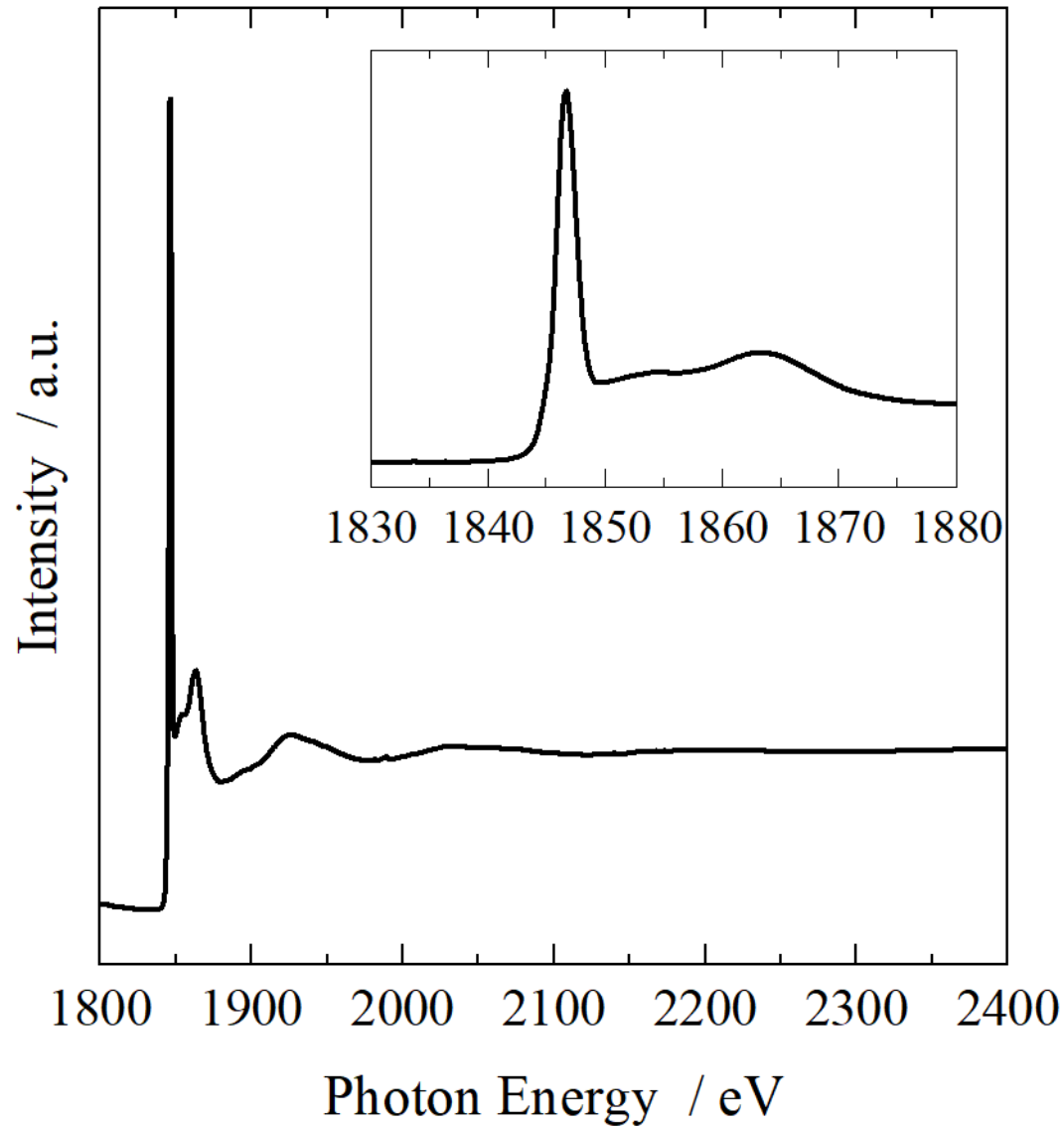
Sample	$\alpha$ -SiC powder
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	2 s
Total points	339 points
Total meas. Time	About 19 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing

## Si K-edge



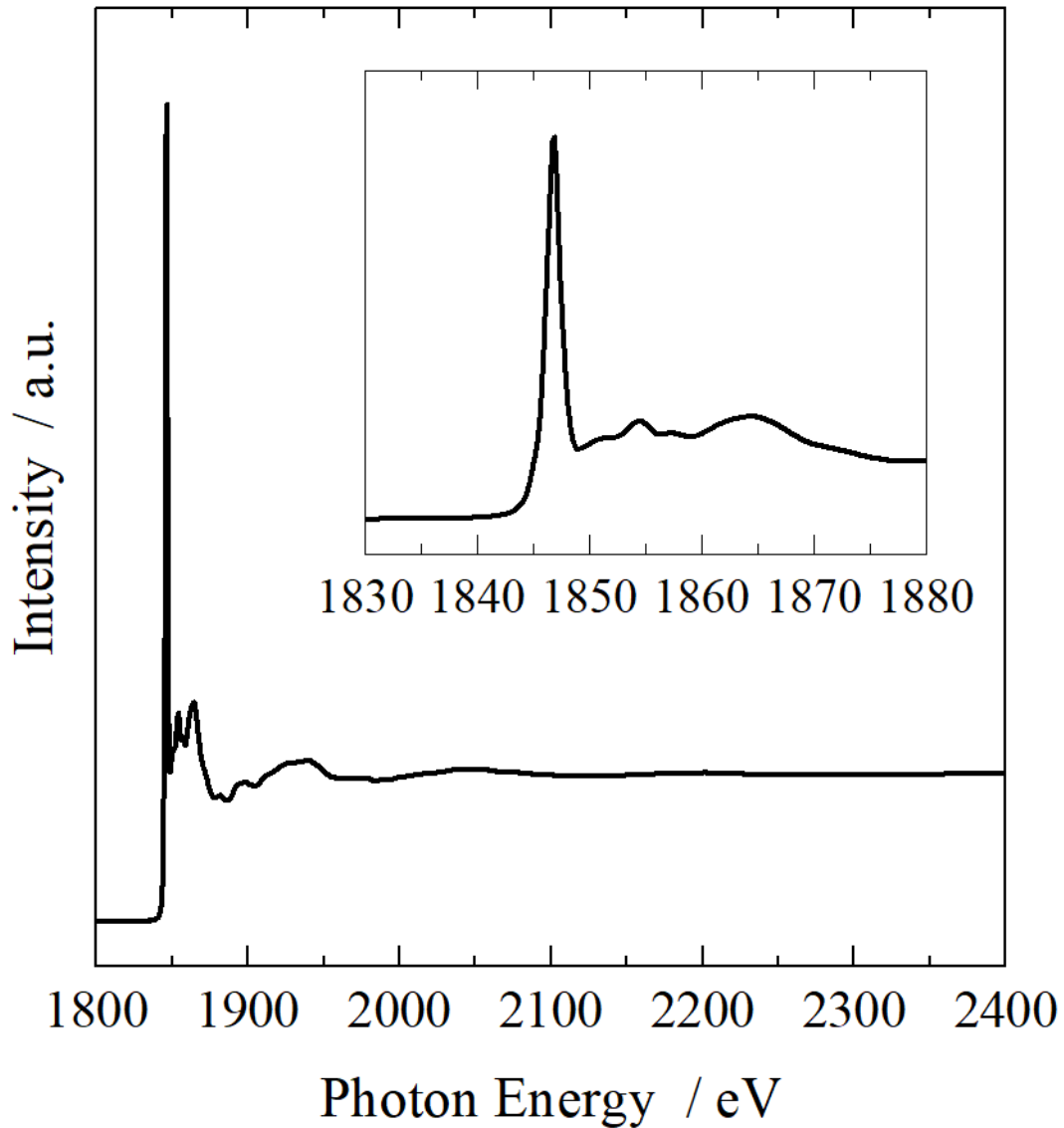
Sample	$\alpha$ -Si <sub>3</sub> N <sub>4</sub> powder
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	2 s
Total points	339 points
Total meas. Time	About 19 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing

## Si K-edge



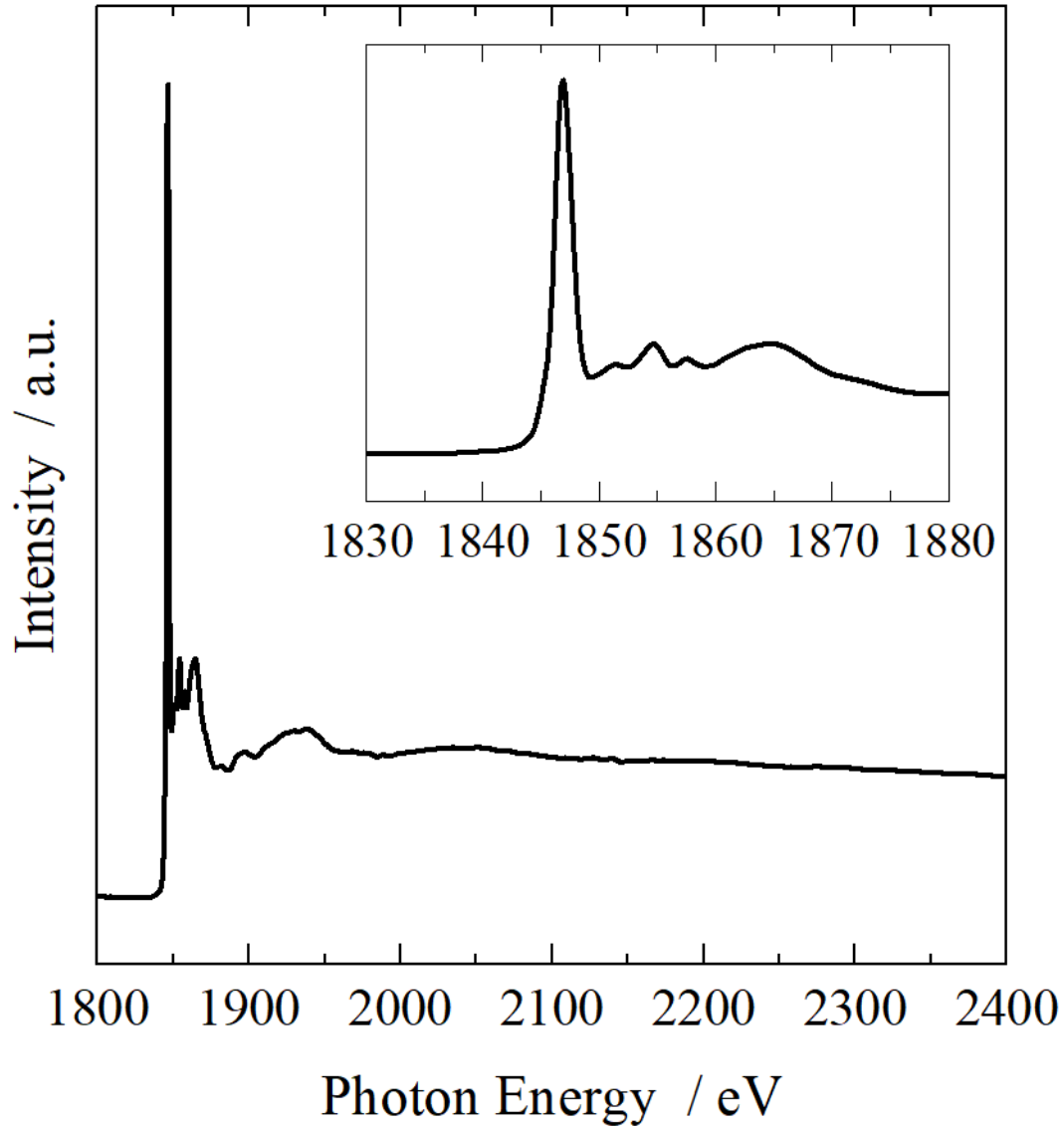
Sample	silica gel powder
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	2 s
Total points	339 points
Total meas. Time	About 19 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing

## Si K-edge



Sample	$\alpha$ -quartz powder
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	2 s
Total points	339 points
Total meas. Time	About 19 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing

## Si K-edge



Sample	$\alpha$ -quartz powder
Beamline	BL05
Monochromator	DCM, InSb(111)
Energy calibration	1839 eV @Si
Energy Range	1800~2400 eV
Dwell time	0.1 s
Total points	339 points
Total meas. Time	About 10 min.
Detection mode	TEY
Detection method	Sample current
Date	2020/07/18
Note	Not focusing